

OCT 17 2005

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**FACSIMILE COVER SHEET**

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| To: Examiner Alexander O. Williams<br>Technology Center 2800 | Total Pages Sent: 2<br>(including cover sheet) |
| Facsimile Number: 571-273-8300                               | Transmission Date: October 17, 2005            |

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

Applicant: Schulze, et al. Docket No.: 115747-0003//  
2002P50544US

Serial No: 10/753,604 Art Unit: 2826

Date Filed: January 8, 2004

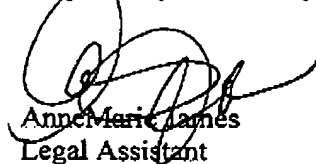
Title: Method for the Repair of Defects in Photolithographic Masks for Patterning  
Semiconductor Wafers

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- Certification of Facsimile Transmission (1 page)
- Election (1 page)

Respectfully submitted,

  
AnneMarie James  
Legal Assistant**Confirmation Respectfully Requested**

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## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

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|-------------|---|-------------|-------------------------------|
| Applicant:  | Schulze, et al.   | Docket No.: | 115747-0003//<br>2002P50544US |
| Serial No.: | 10/753,604  | Art Unit:   | 2826                          |
| Filed:      | 1/8/2004  | Examiner:   | Alexander O. Williams         |
| Title:      | Method for the Repair of Defects in Photolithographic Masks for Patterning Semiconductor Wafers |             |                               |

Date: October 17, 2005

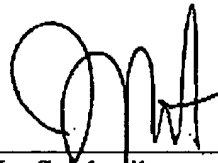
Mail Stop Amendment  
Commissioner for Patents  
P. O. Box 1450  
Alexandria, VA 22313-1450

ELECTION

Dear Sir:

In response to the restriction requirement set forth in the Office Action mailed on September 29, 2005, the Applicant hereby elects Group II (claims 1-18 and 29-47) for further prosecution in the above patent application.

Respectfully submitted,



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